



IFW

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**Applicants:** Matthew J. Breitwisch, et al.

**Docket:** BUR920040015US1 (17427)

**Serial No.:** 10/710821

**Dated:** June 7, 2004

**Filed:** 08/05/04

**For:** ISOLATED FULLY DEPLETED  
SILICON-ON-INSULATOR REGIONS BY  
SELECTIVE ETCH

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

Sir:

In accordance with 37 C.F.R. §§ 1.97 and 1.98, it is requested that the following reference, which is also listed on the attached Form PTO-1449, be made of record in the above-identified case.

1. M.Q. Huda, et al., "Technique for Large Elevation of Source/Drain Using Implantation Mediated Selective Etching", Electrochemical and Solid-State Letters, pp. G117-G118 (2003); and
  
2. Japanese Laid-Open Patent Application No. JP7007075A, filed on October 1, 1995, with English Language Translation.

**CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)**

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner of Patents and Trademarks, P.O. Box 1450, Alexandria, VA 22313-1450 on

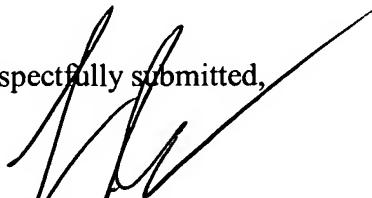
Dated:

8/13/04

8/13/04  
P de Langis  
P de Langis

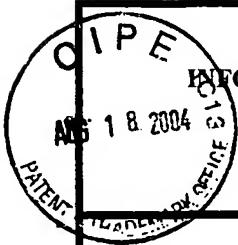
Applicants are submitting copies of the cited references, along with an English Abstract which explains the pertinence of the reference.

Inasmuch as this Information Disclosure Statement is being submitted in accordance with the schedule set out in 37 C.F.R. § 1.97(b), no petition, certification or fee is required.

Respectfully submitted,  
  
Leslie S. Szivos Ph.D.  
Registration No. 39,394

SCULLY, SCOTT, MURPHY & PRESSER  
400 Garden City Plaza  
Garden City, New York 11530  
(516) 742-4343

LSS:HAH:kc



**INFORMATION DISCLOSURE CITATION**  
(Use several sheets if necessary)

ABG 1 8. 2004

**Docket Number (Optional)**

**Application Number**

**Applicant(s)**

Matthew J. Breitwisch, et al.

**Filing Date**

08/05/04

**Group Art Unit**  
**Unassigned**

## U.S. PATENT DOCUMENTS

## FOREIGN PATENT DOCUMENTS

REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	JP7007075A	10/1/95	Japan				

**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

M.Q. Huda, et al., "Technique for Large Elevation of Source/Drain Using Implantation Mediated Selective Etching", Electrochemical and Solid-State Letters, pp. G117-G118 (2003).

**EXAMINER**

**DATE CONSIDERED**

**EXAMINER:** Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.